

03500.016291.



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

RYUJI BIRO, ET AL.

Application No.: 10/098,569

Filed: March 18, 2002

For: VACUUM DEPOSITION SYSTEM)
AND THIN-FILM DEPOSITION
PROCESS

)
:
Examiner: Not Yet Assigned

)
:
Group Art Unit: 1734

)
:
March 3, 2002

Commissioner for Patents
Washington, D.C. 20231

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INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.

The concise explanation of relevance for the non-English document JP 8060347 is provided in the English abstract attached.

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The Examiner's attention is also directed to the following U.S. Applications:

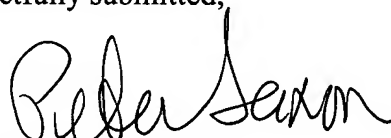
<u>APPLICATION NO.</u>	<u>FILING DATE</u>	<u>GROUP ART UNIT</u>
08/821,435	03/27/97	1753

A copy of each cited Application is enclosed.

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants

Registration No.

24947

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